

AP5 Rec'd PCT/PTO 27 SEP 2006

PATENT

8007-1118

10/594567

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Masaru HOSOKAWA et al.

Conf.

Application No. **NEW NATIONAL PHASE**

Group

Filed September 27, 2006

Examiner

MATERIAL FOR CHEMICAL VAPOR DEPOSITION AND THIN FILM FORMING  
METHOD

**PRELIMINARY AMENDMENT**

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 27, 2006

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims which begin on page 2 of this paper.

**Remarks** begin on page 5 of this paper.